

# SECTION B

NMOS & CMOS inverters and Gates  
Lamda Base rule.

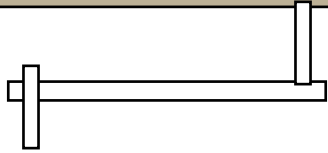

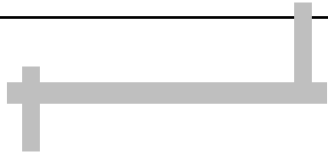


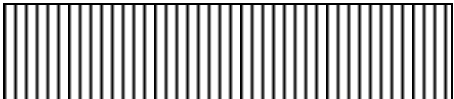






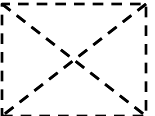
# Topic Covered

- **NMOS & CMOS INVERTER AND GATES :**  
NMOS & CMOS inverter – Determination of pull up /
- pull down ratios – Stick diagram – Lamda based rules – Super buffers – BiCMOS & steering logic

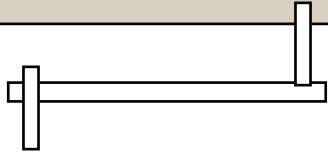



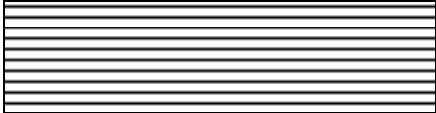

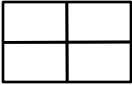



# Stick Diagrams

- VLSI design aims to translate circuit concepts onto silicon
- stick diagrams are a means of capturing topography and layer information - simple diagrams
- Stick diagrams convey layer information through color codes (or monochrome encoding)

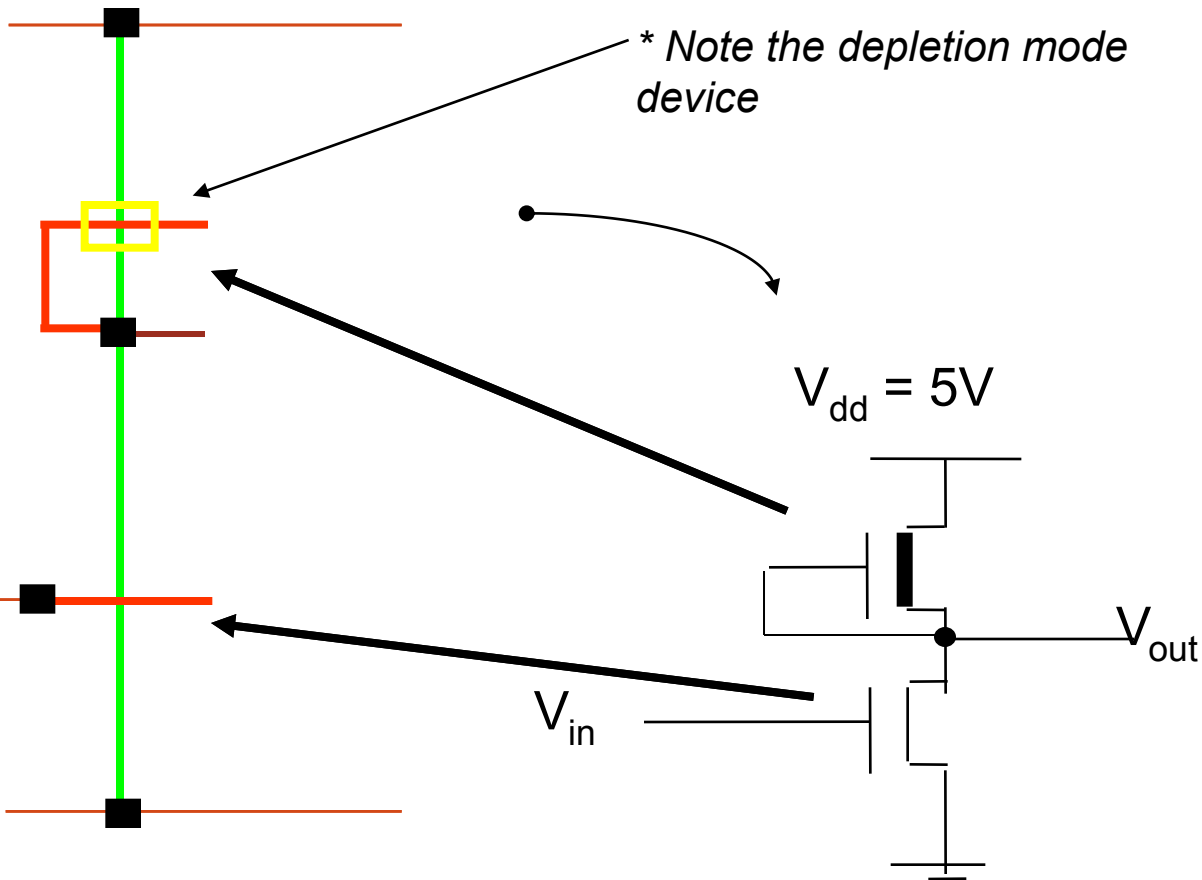
# Encoding for nMOS

Stick Encoding	Layer	Mask Layout Encoding
	Thinox	
	Polysilicon	
	Metal1	
	Contact cut	
NOT applicable	Overglass	
	Implant	
	Buried contact	

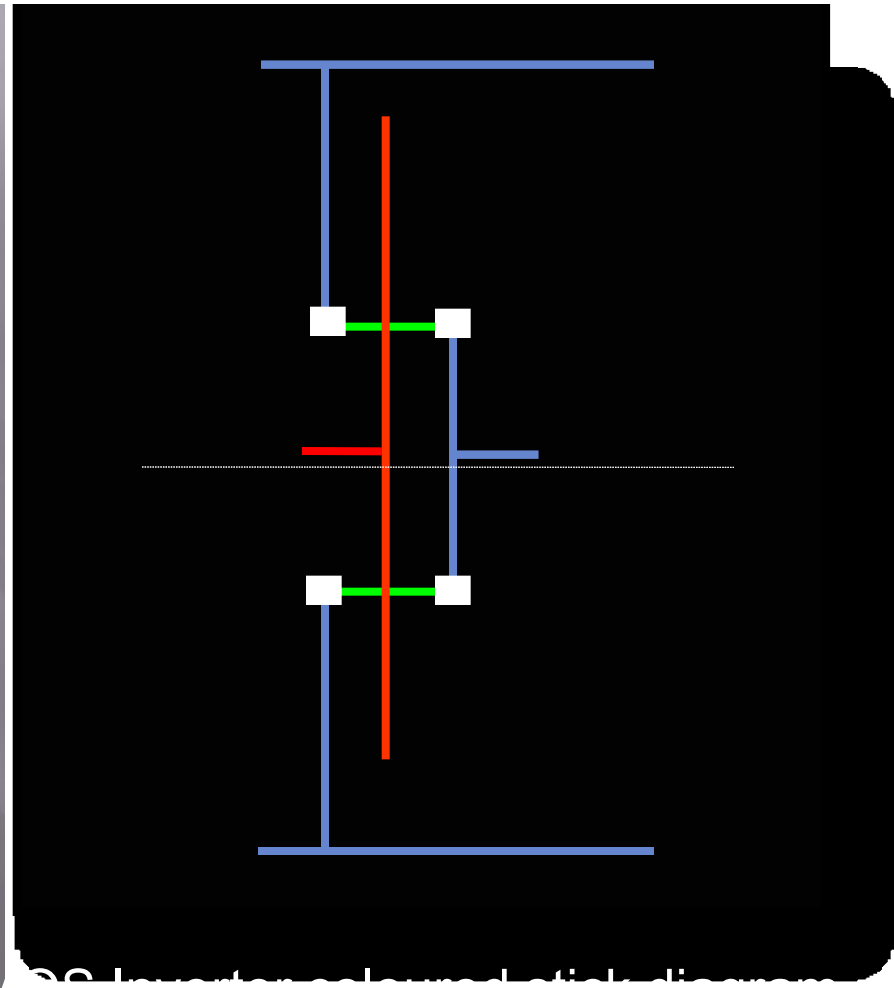
# Encoding for pMOS

Stick Encoding	process	Layer	Mask Layout Encoding
		<b>P-Diffusion</b>	
Not Shown in Stick Diagram		<b>P+ Mask</b>	
		<b>Met12</b>	
		<b>VIA</b>	
<b>Demarcation Line</b> 		<b>P-Well</b>	
		<b>Vdd or GND CONTACT</b>	

# For reference : an nMOS Inverter coloured stick diagram

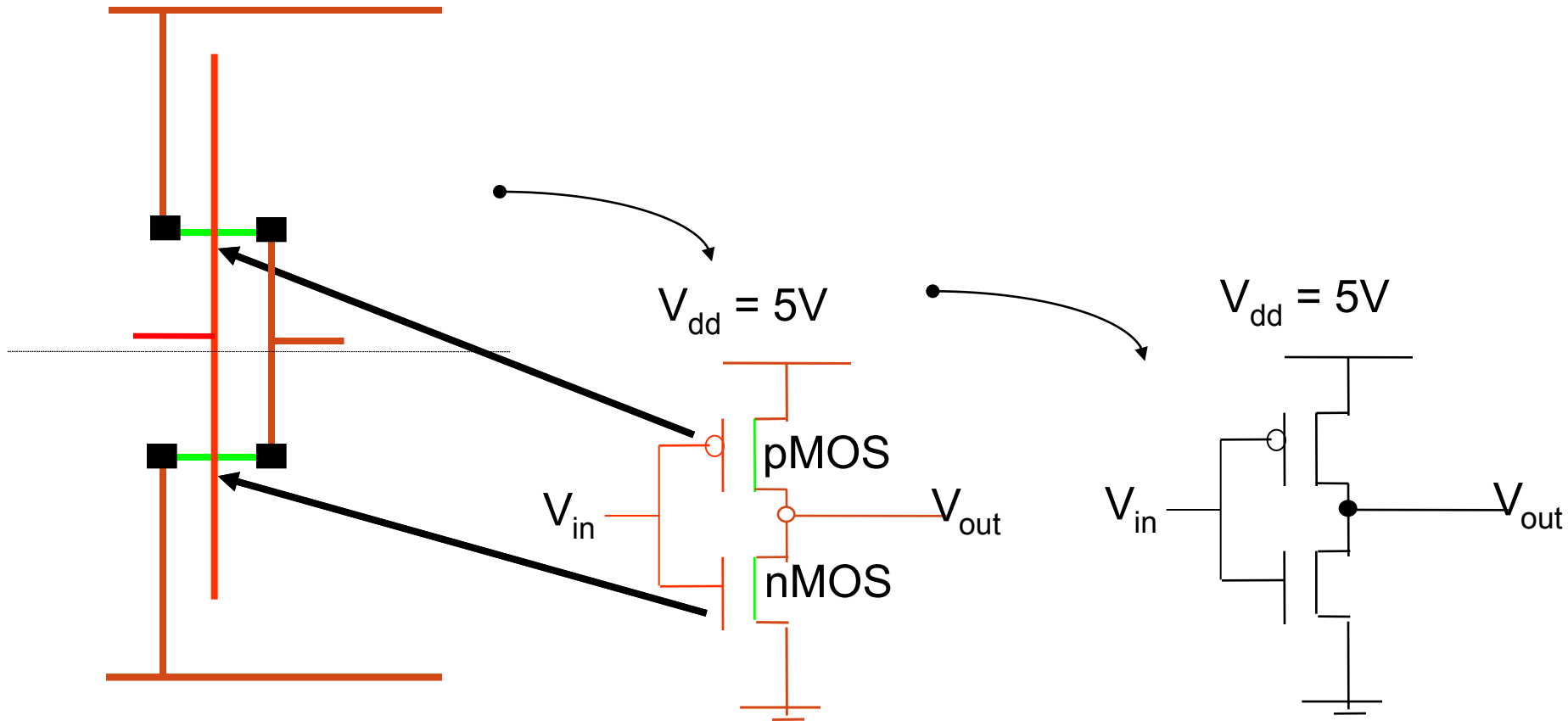


Only metal and polysilicon can cross the demarcation line.



CMOS Inverter coloured stick diagram

# Stick diagram -> CMOS transistor circuit





# Lambda ( $\lambda$ )-based design rules

All paths in all layers will be dimensioned in  $\lambda$  units and subsequently  $\lambda$  can be allocated an appropriate value compatible with the feature size of the fabrication process.

# TRANSISTOR DESIGN RULES

Thinox

n-

p-

Metal 1

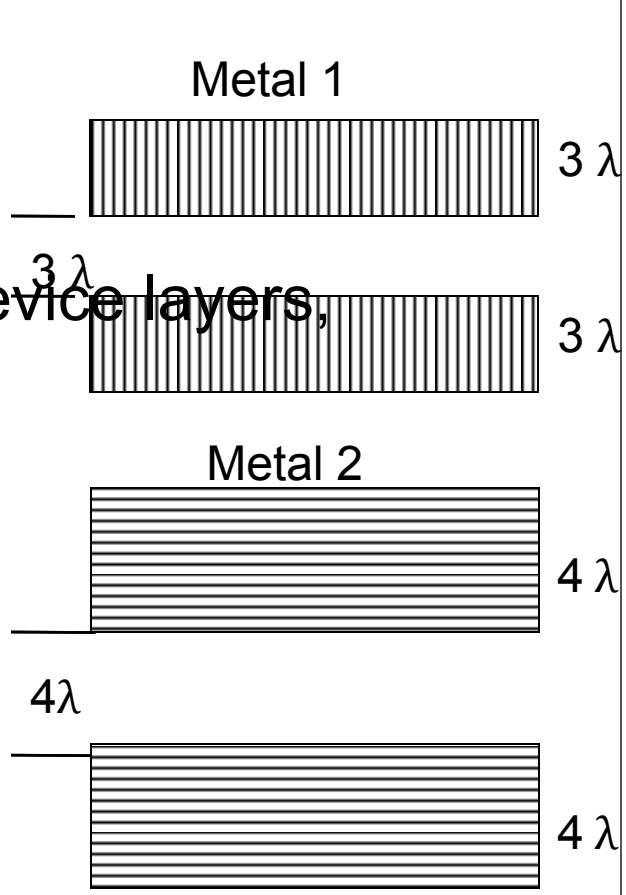
$3\lambda$

$3\lambda$

$4\lambda$

$4\lambda$

Metal 2

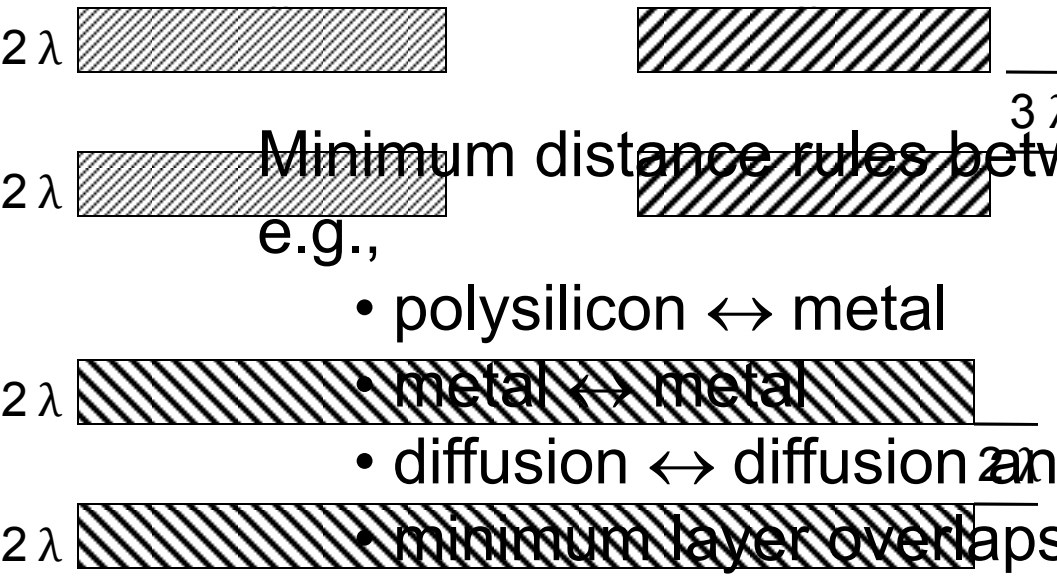


Minimum distance rules between device layers,

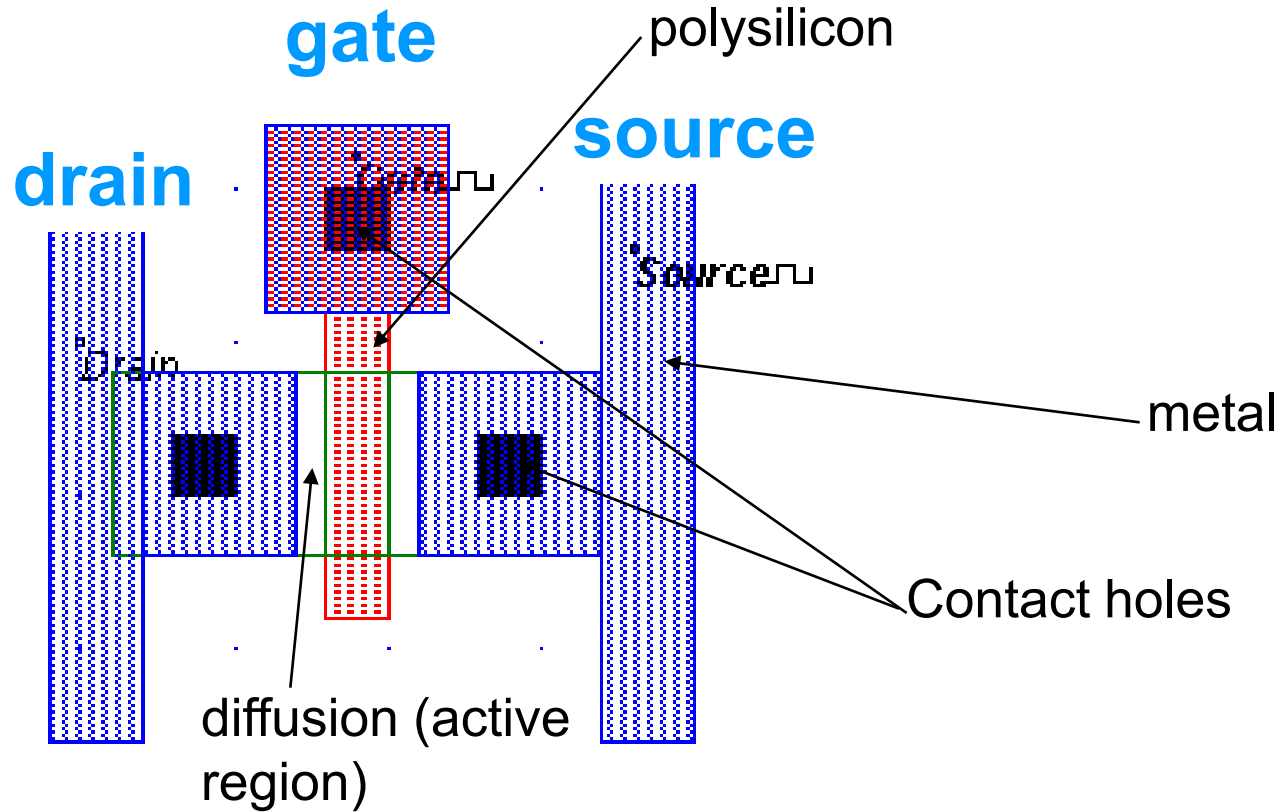
e.g.,

- polysilicon ↔ metal
- metal ↔ metal
- diffusion ↔ diffusion and polysilicon
- minimum layer overlaps

are used during layout



# nMOS transistor mask representation



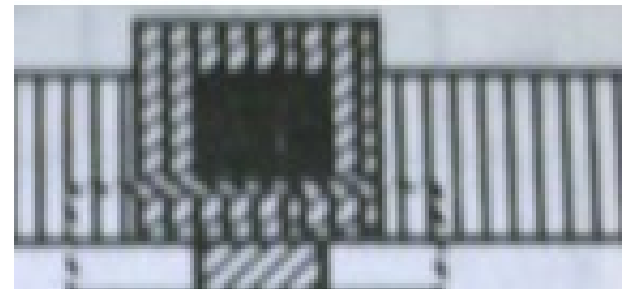
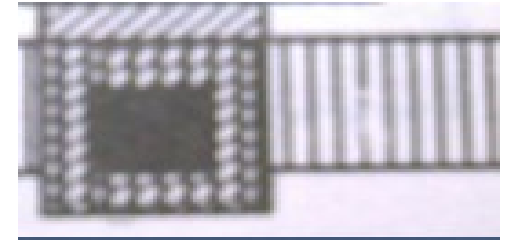
# Contact Cuts

- Three possible approaches –

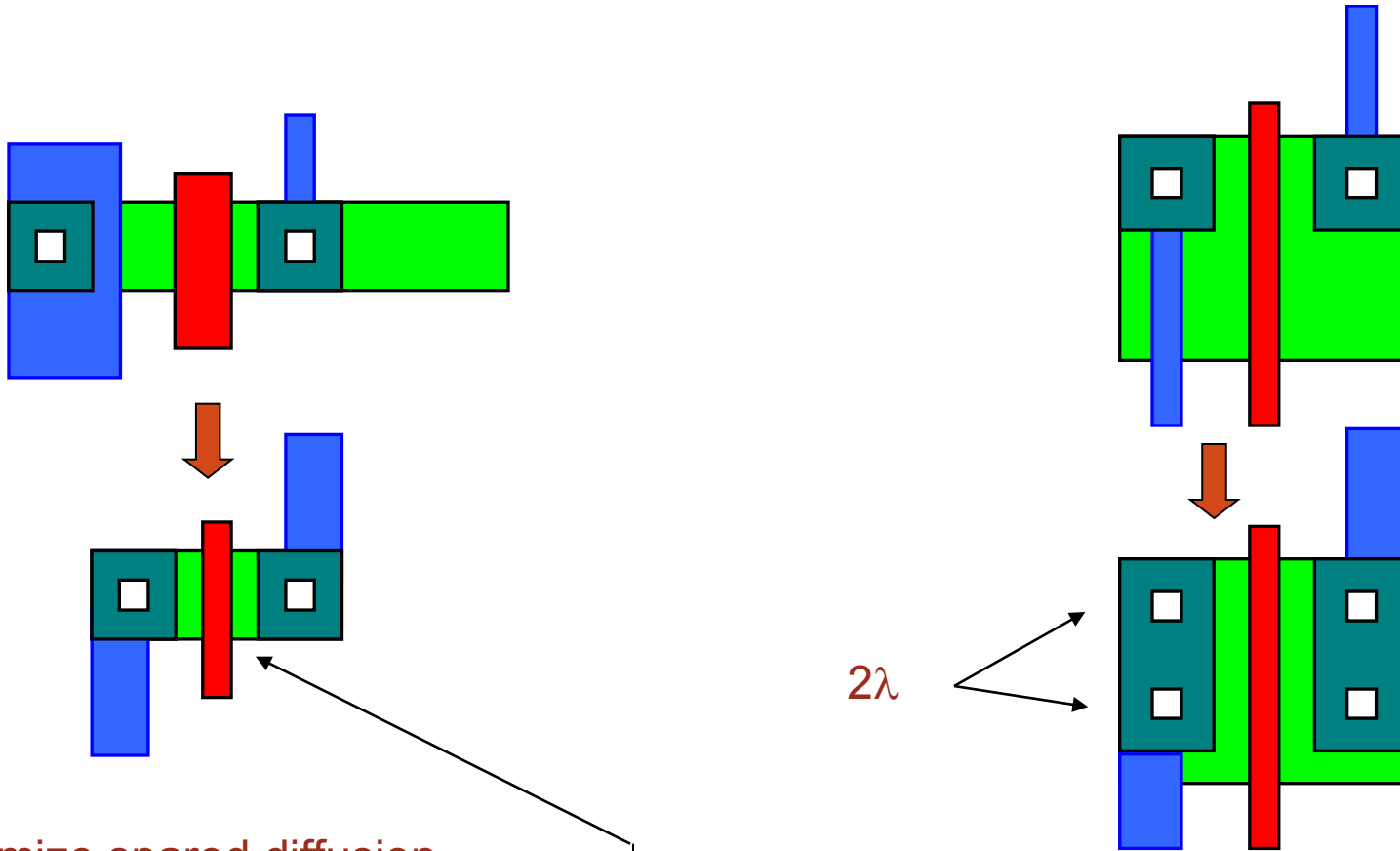
1. Poly to Metal

2. Metal to Diffusion

3. Buried contact (poly to diff) or butting contact (poly to diff using metal)



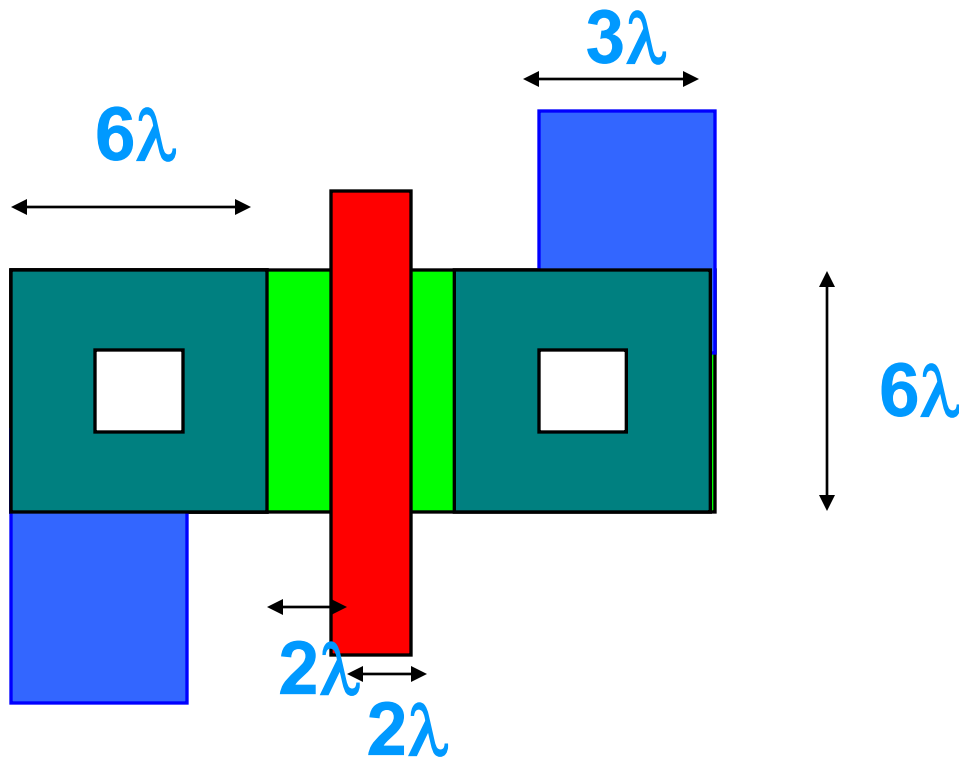
# Layout Design rules & Lambda ( $\lambda$ )



- Minimize spaced diffusion
- Use minimum poly width ( $2\lambda$ )

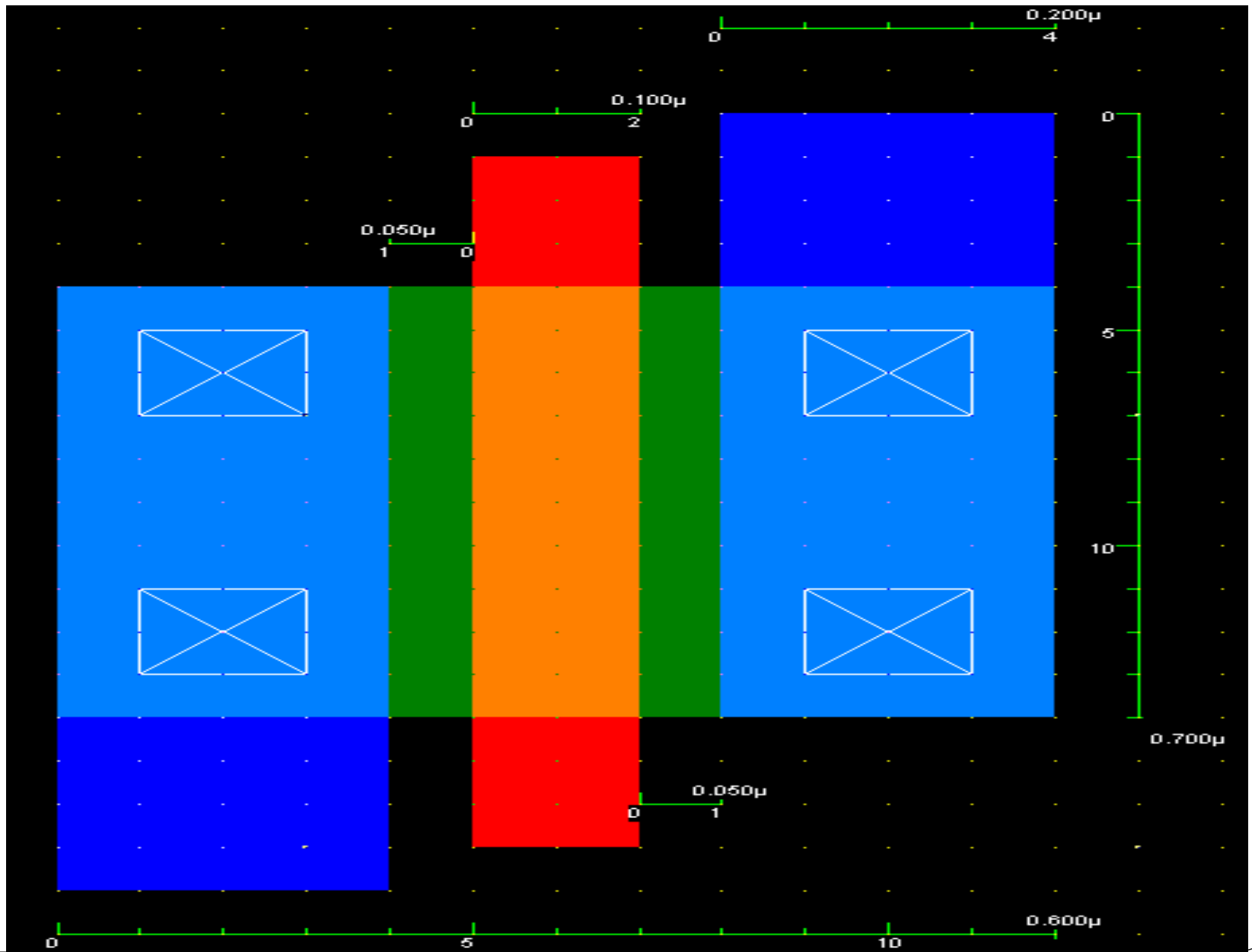
- Width of contacts =  $2\lambda$
- Multiply contacts

# Layout Design rules & Lambda ( $\lambda$ )

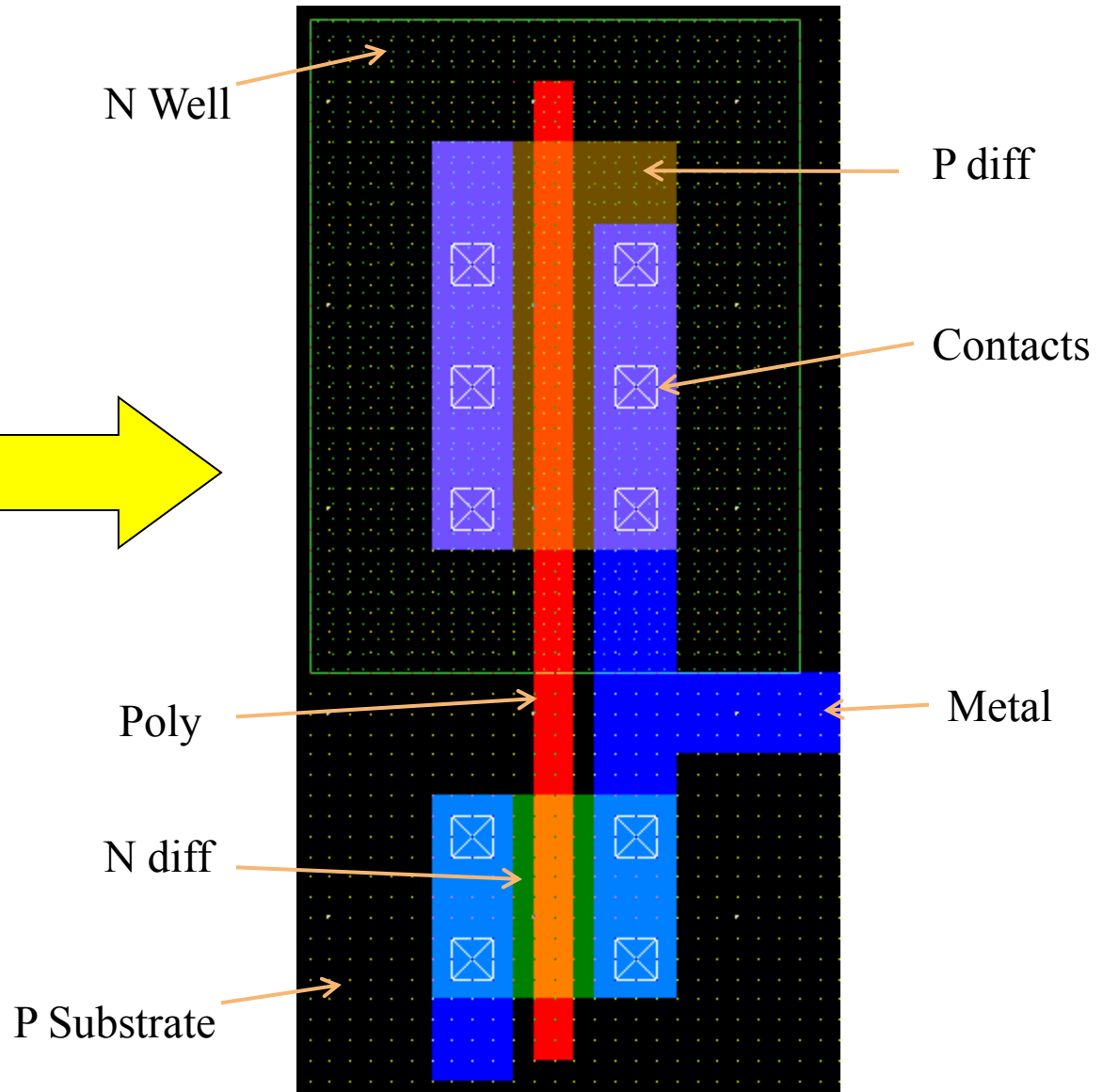
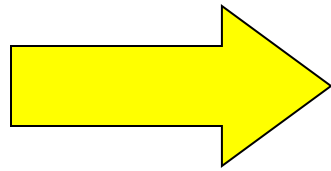
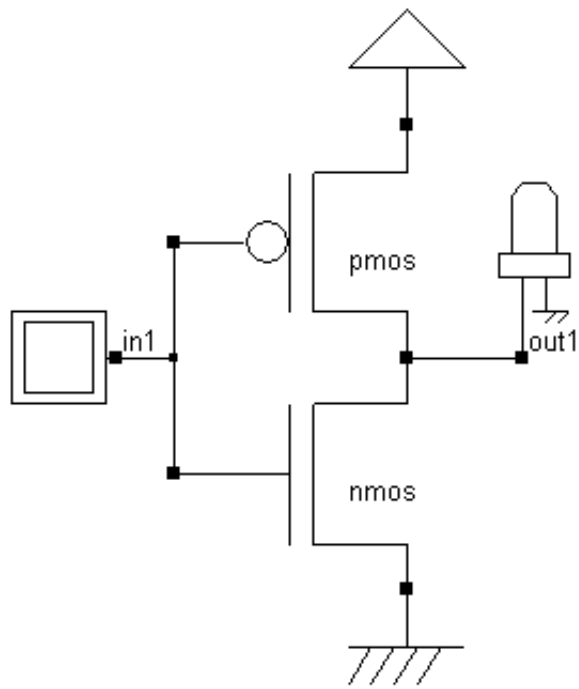


All device mask dimensions are based on multiples of  $\lambda$ , e.g., polysilicon minimum width =  $2\lambda$ . Minimum metal to metal spacing =  $3\lambda$

# Layout Design rules & Lambda ( $\lambda$ )

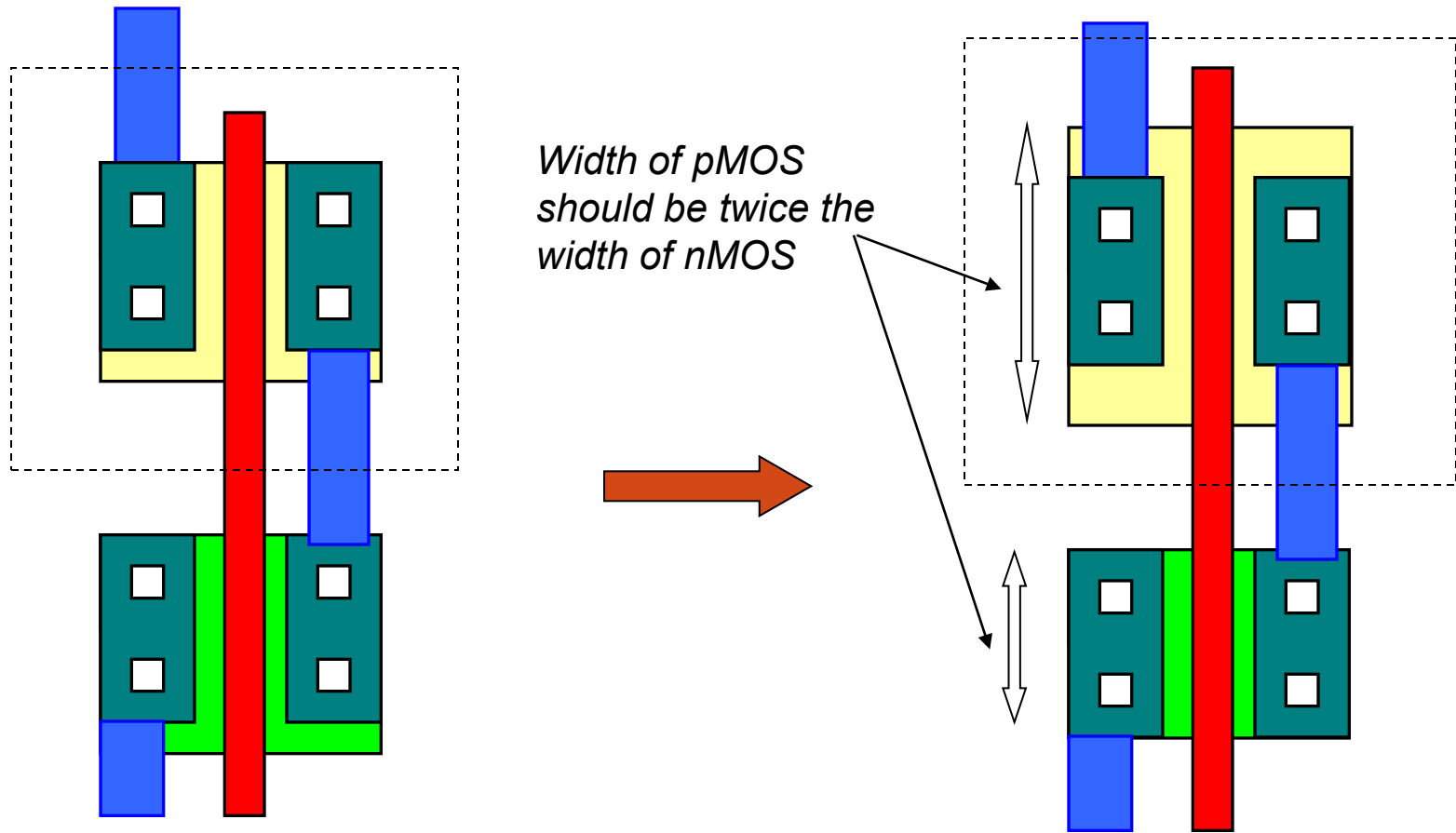


# CMOS Layout





# Layout Design rules & Lambda ( $\lambda$ )



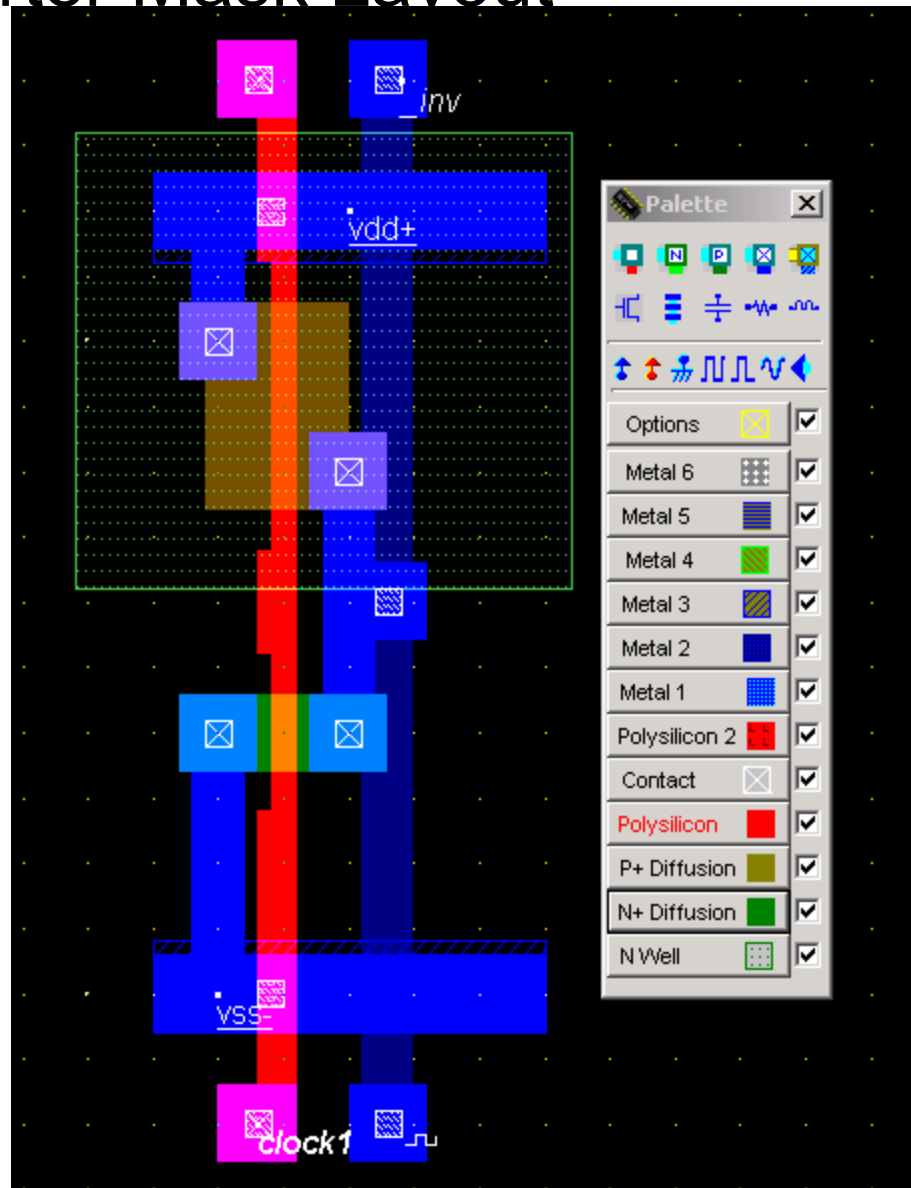
- Same N and P alters symmetry

- L min
- $W_{pmos} = 2 W_{nmos}$

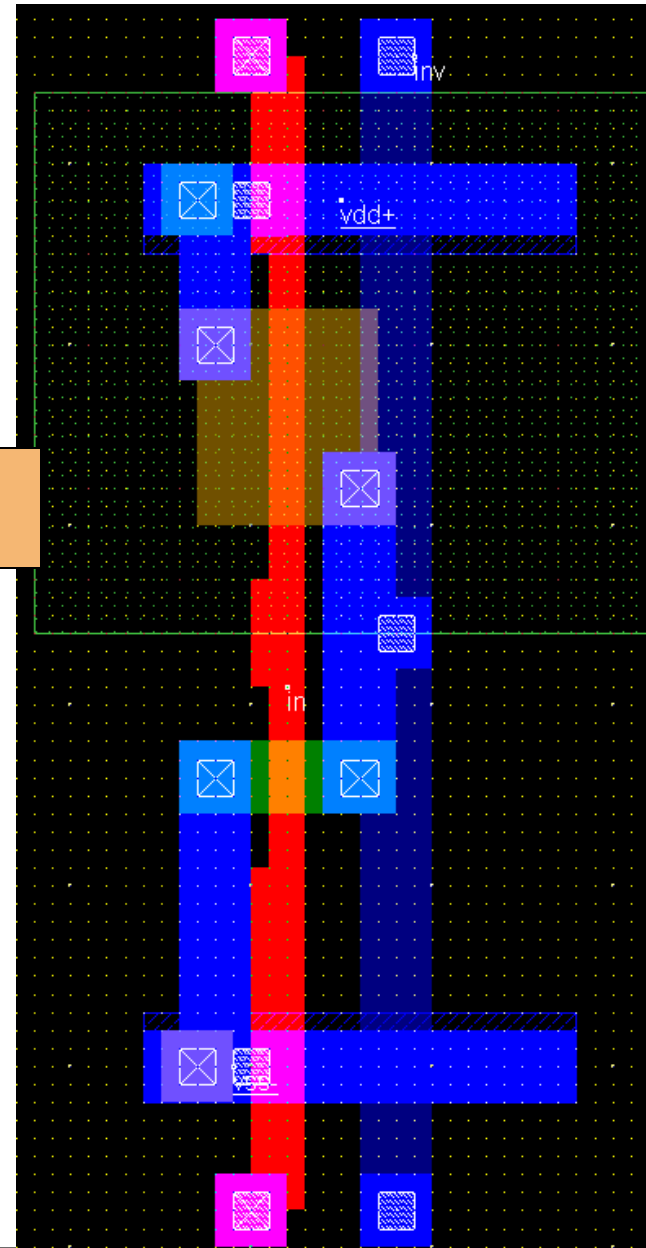
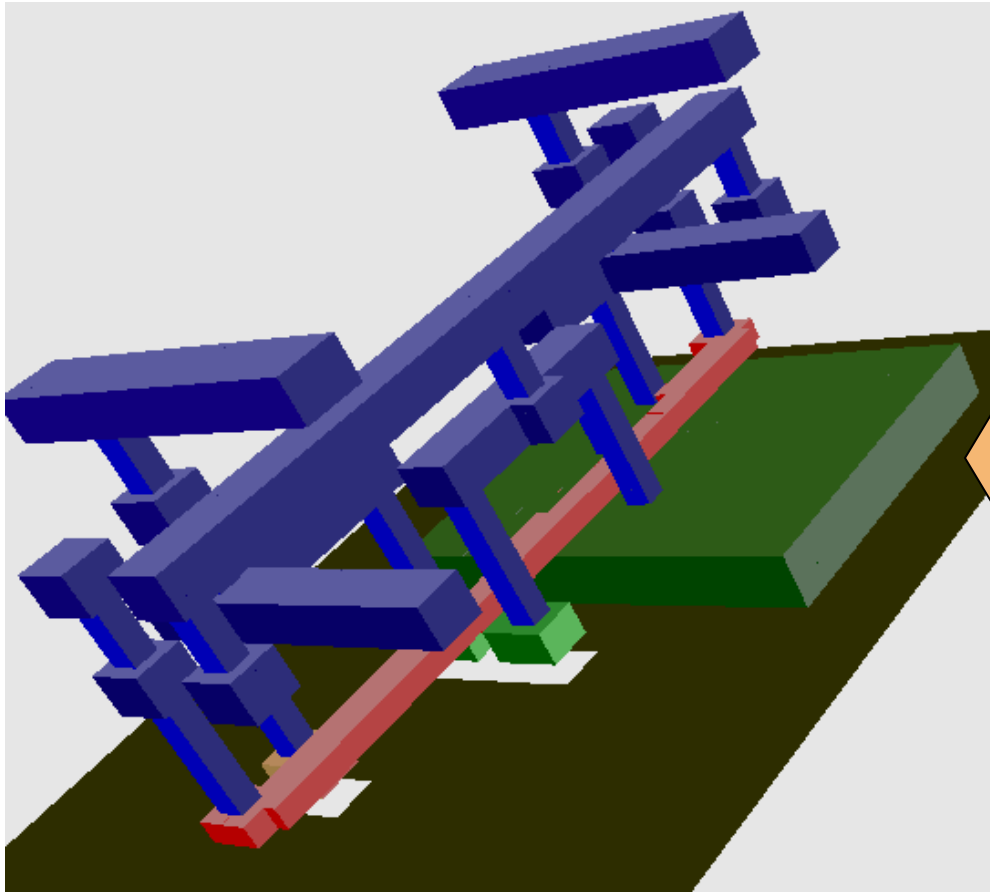
# Lambda Based Design Rules

- Design rules based on single parameter,  $\lambda$
- Simple for the designer
- Wide acceptance
- Provide feature size independent way of setting out mask
- Minimum feature size is defined as  $2\lambda$
- Used to preserve topological features on a chip
- Prevents shorting, opens, contacts from slipping out of area to be contacted

# CMOS Inverter Mask Layout

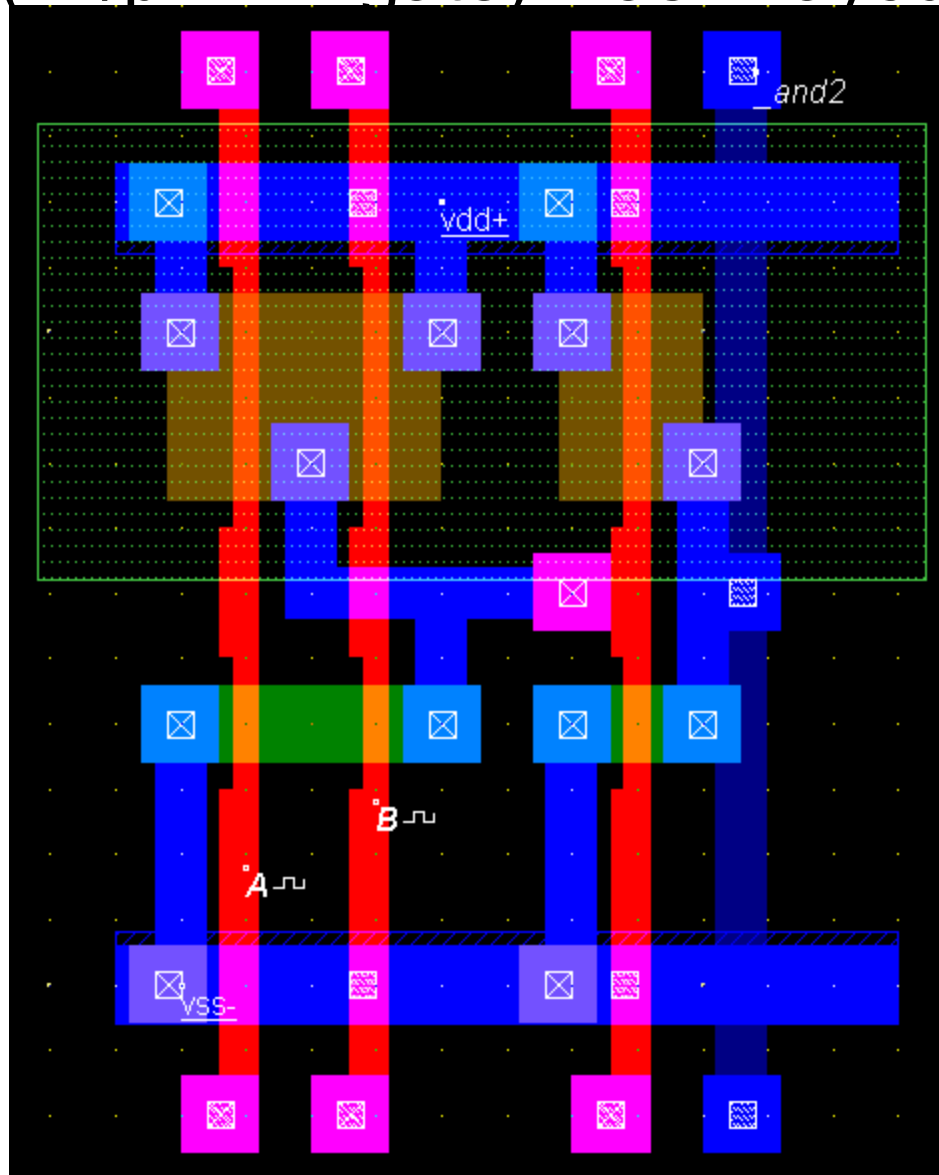


# MOS Layout Design



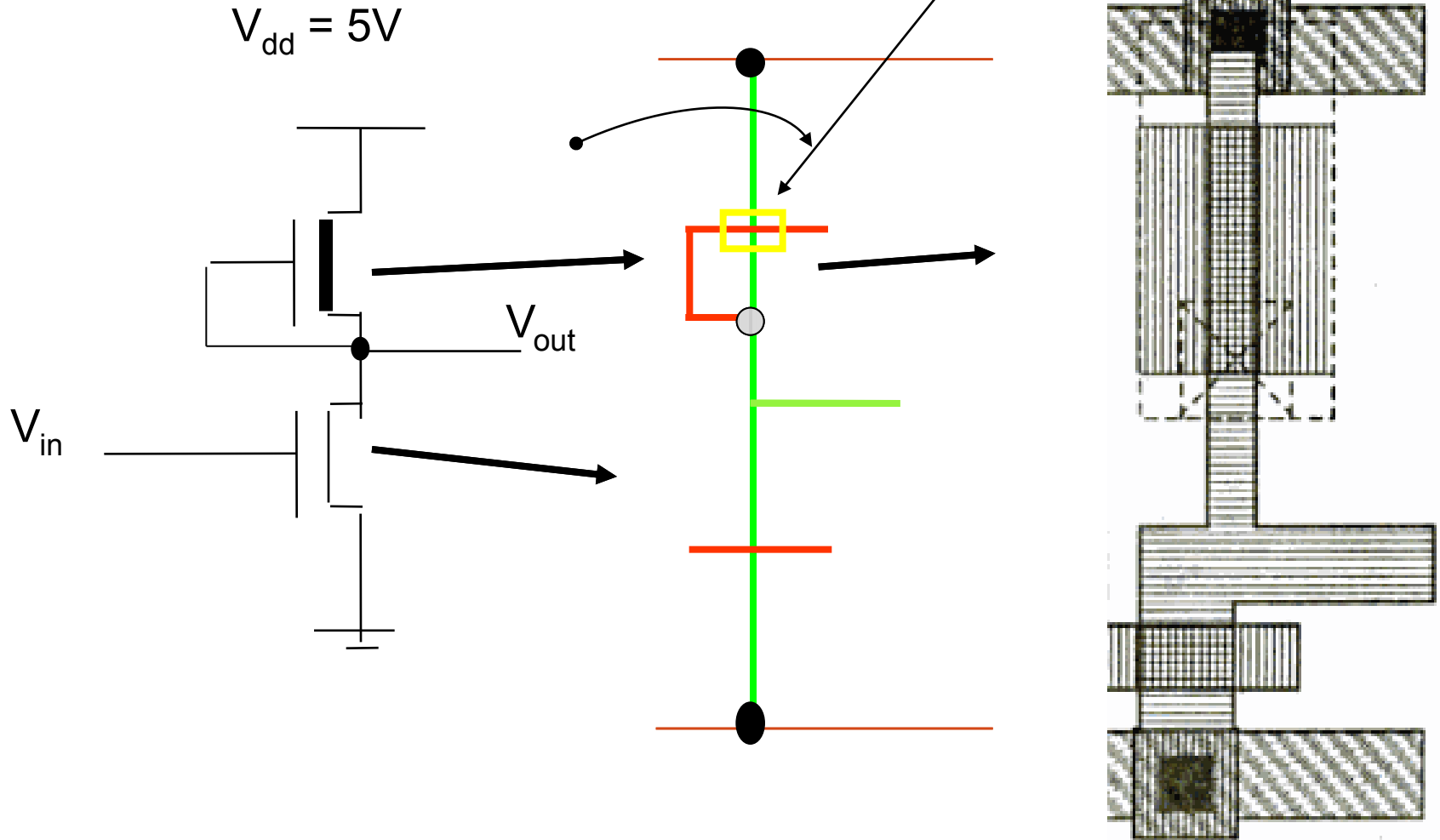
- CMOS IC are designing using stick diagrams.
- Different color codes for each layer.
- Lamda/micron grid.

# CMOS AN2 (2 i/p AND gate) Mask Layout

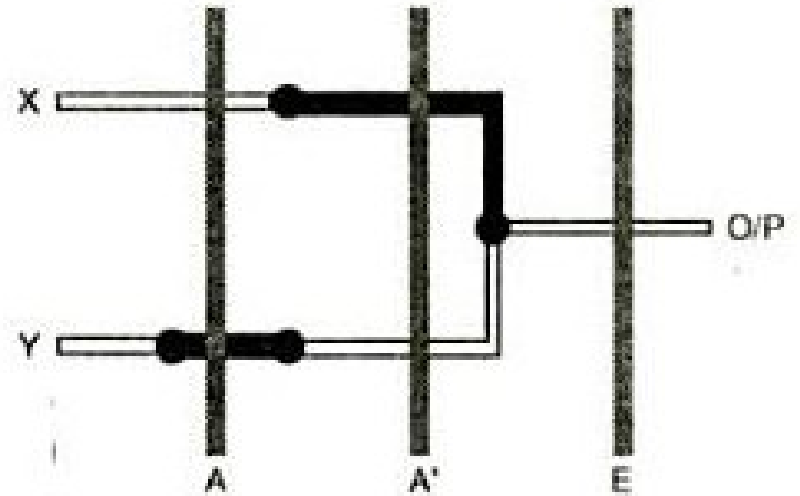
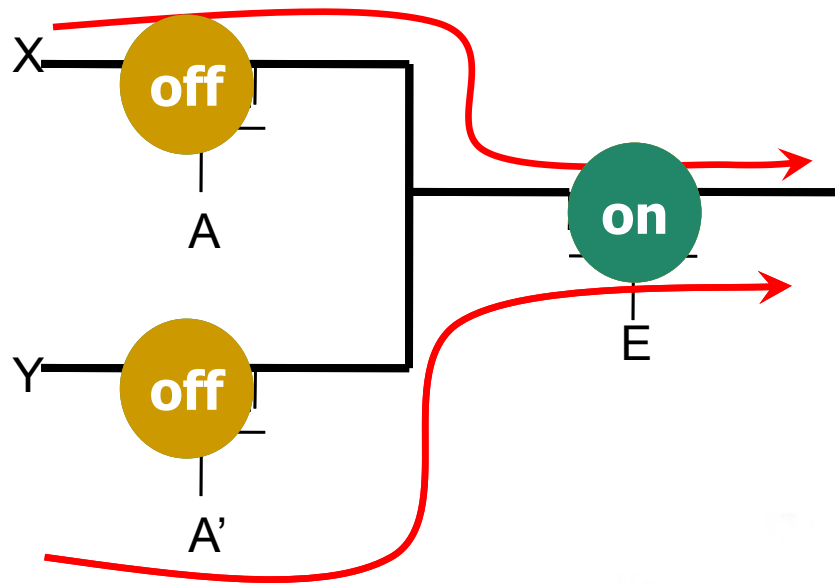


# nMOS Inverter coloured stick diagram

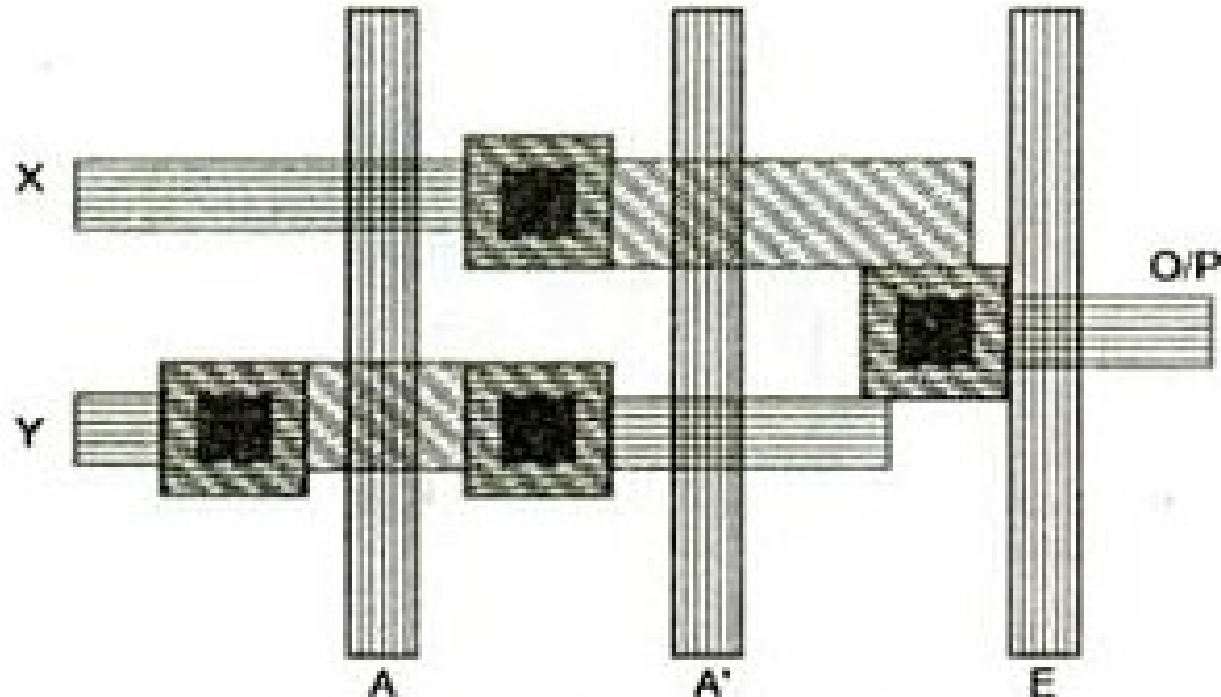
*\* Note the depletion mode device*



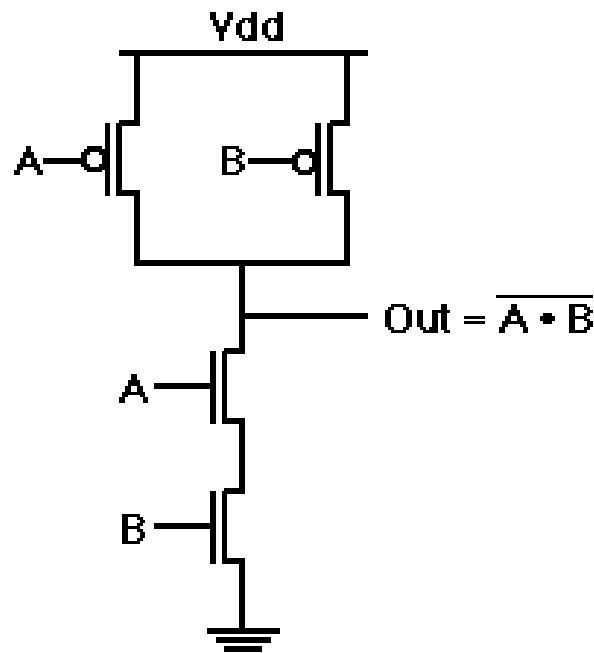
# Two-way selector with enable



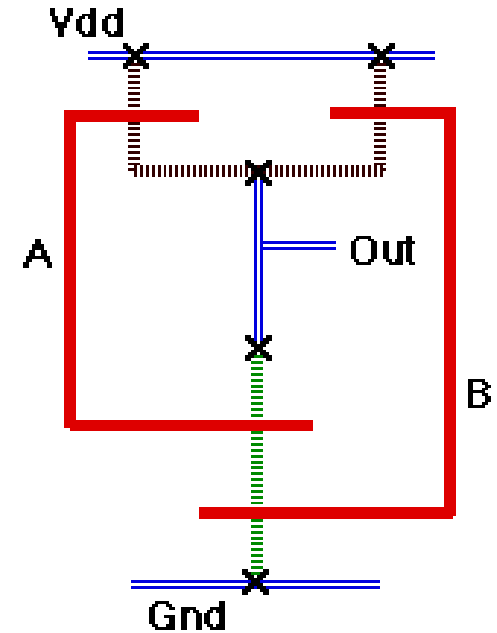
$E=0$   
 $A=0|1$



# Static CMOS NAND gate



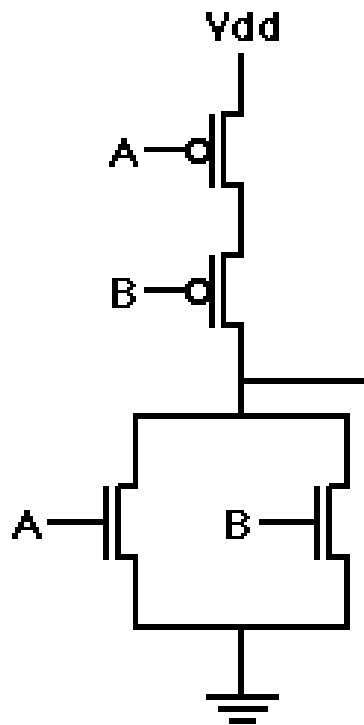
A	B	$\overline{A \cdot B}$
0	0	1
0	1	1
1	0	1
1	1	0



1. Pull-down: Connect to ground if  $A=1$  AND  $B=1$
2. Pull-up: Connect to  $V_{dd}$  if  $A=0$  OR  $B=0$

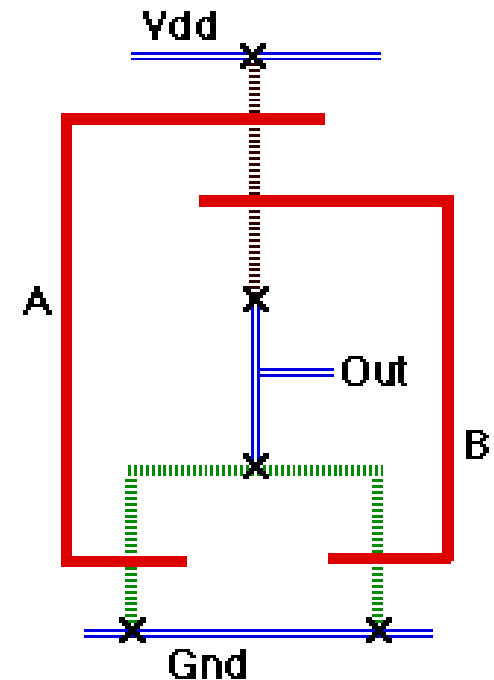


# Static CMOS NOR gate



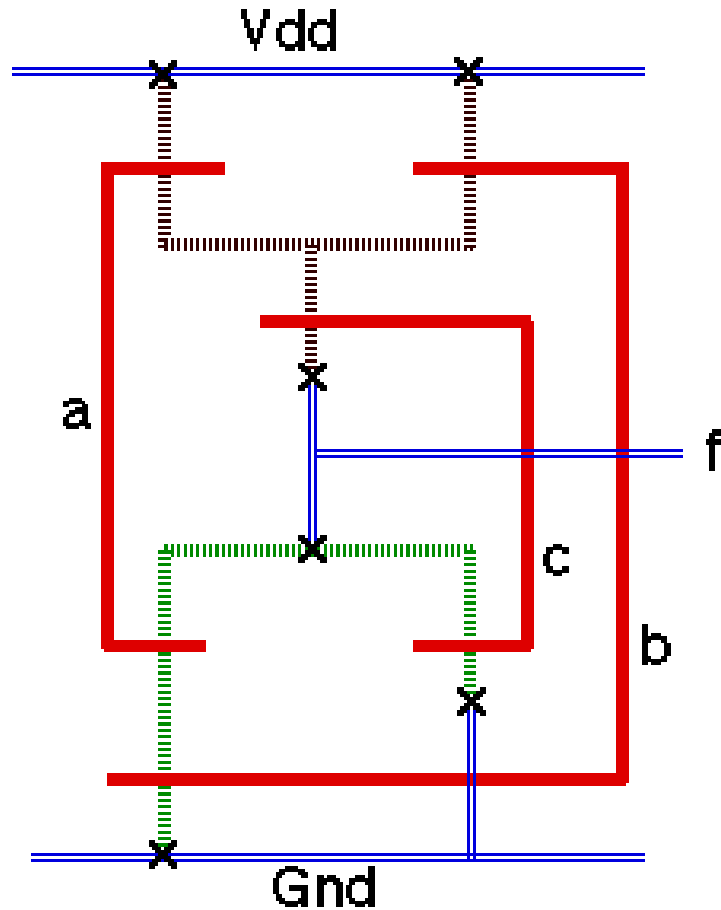
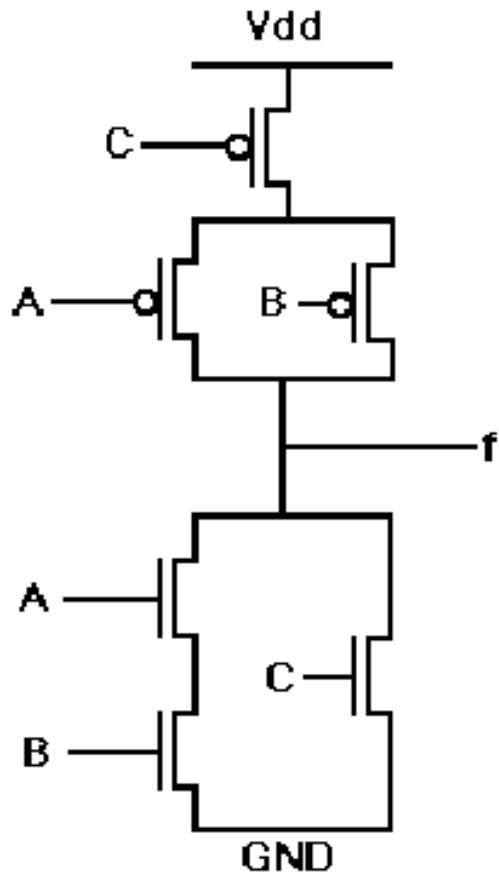
$$\text{Out} = \overline{A+B}$$

A	B	$\overline{A+B}$
0	0	1
0	1	0
1	0	0
1	1	0



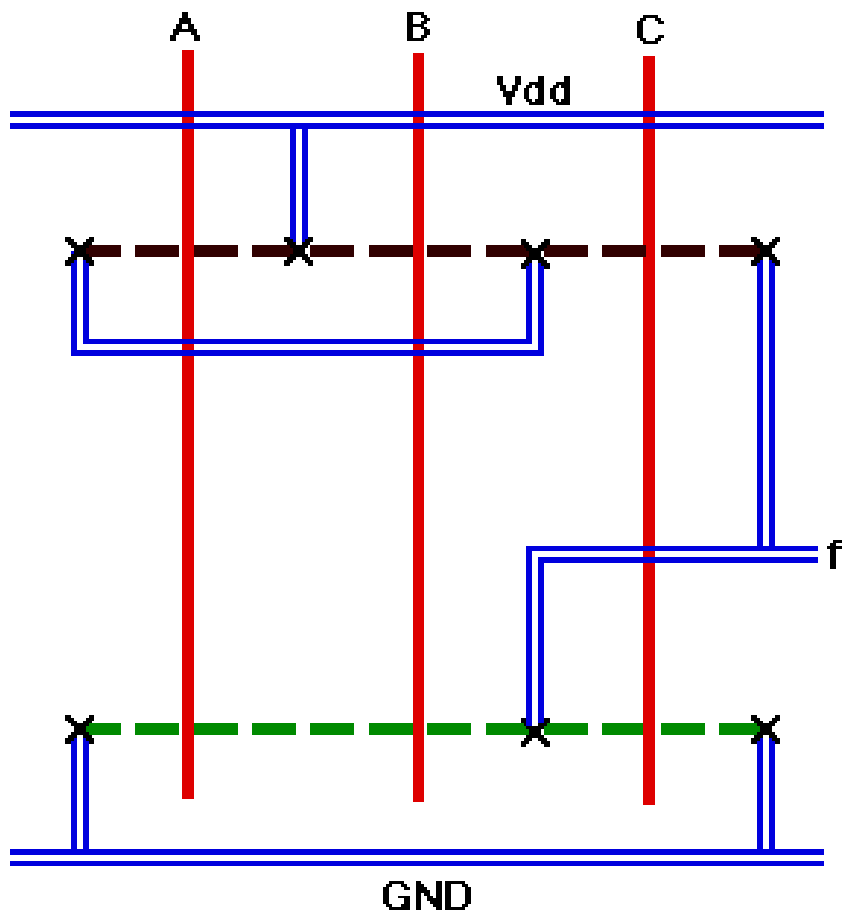
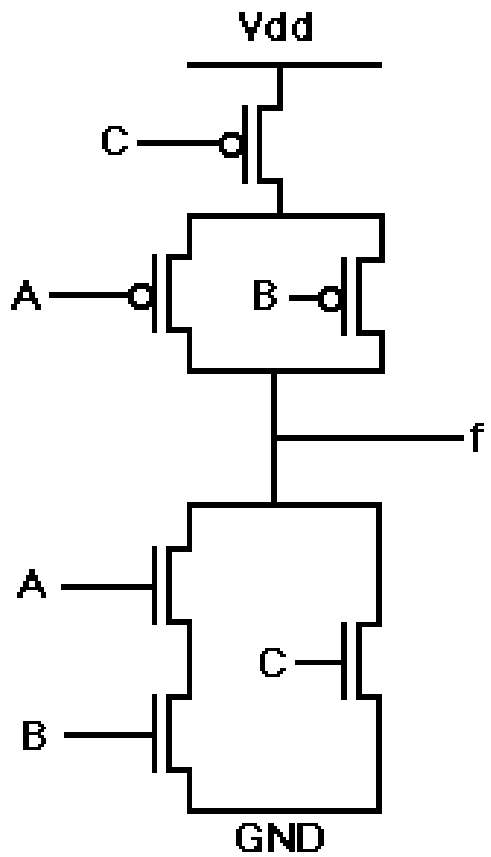
1. Pull-down: Connect to ground if  $A=1$  OR  $B=1$
2. Pull-up: Connect to Ydd if  $A=0$  AND  $B=0$

# Static CMOS Design Example Layout



$$\text{Example: } f = \overline{a \cdot b} + c$$

# Layout 2 (Different layout style to previous but same function being implemented)

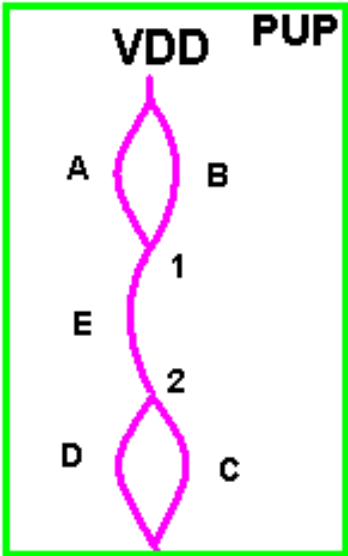


Example:  $f = \overline{a \cdot b} + c$

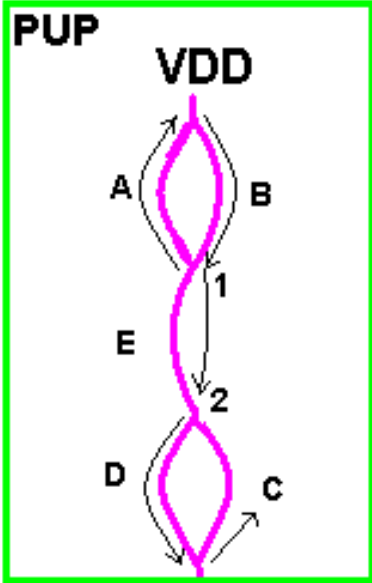
# Complex logic gates layout

- Ex—~~F=AB+E+CD~~
- Eulerpaths
- Circuit to graph (convert)
  - 1) Vertices are source/Drain connections
  - 2) Edges are transistors
- Find p and n Eulerpaths

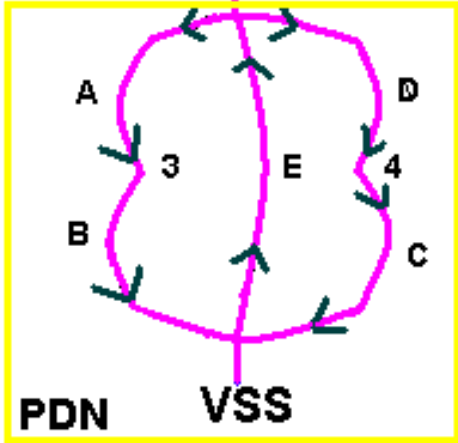
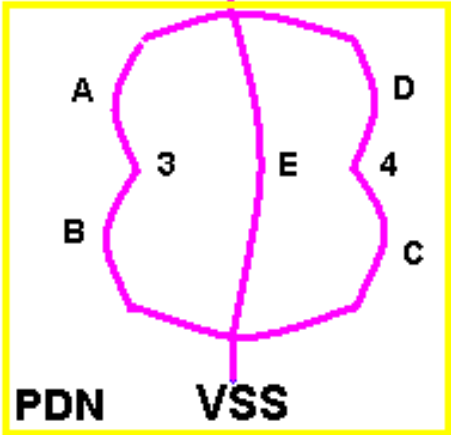
$$F = (AB)+E+(CD)$$



output



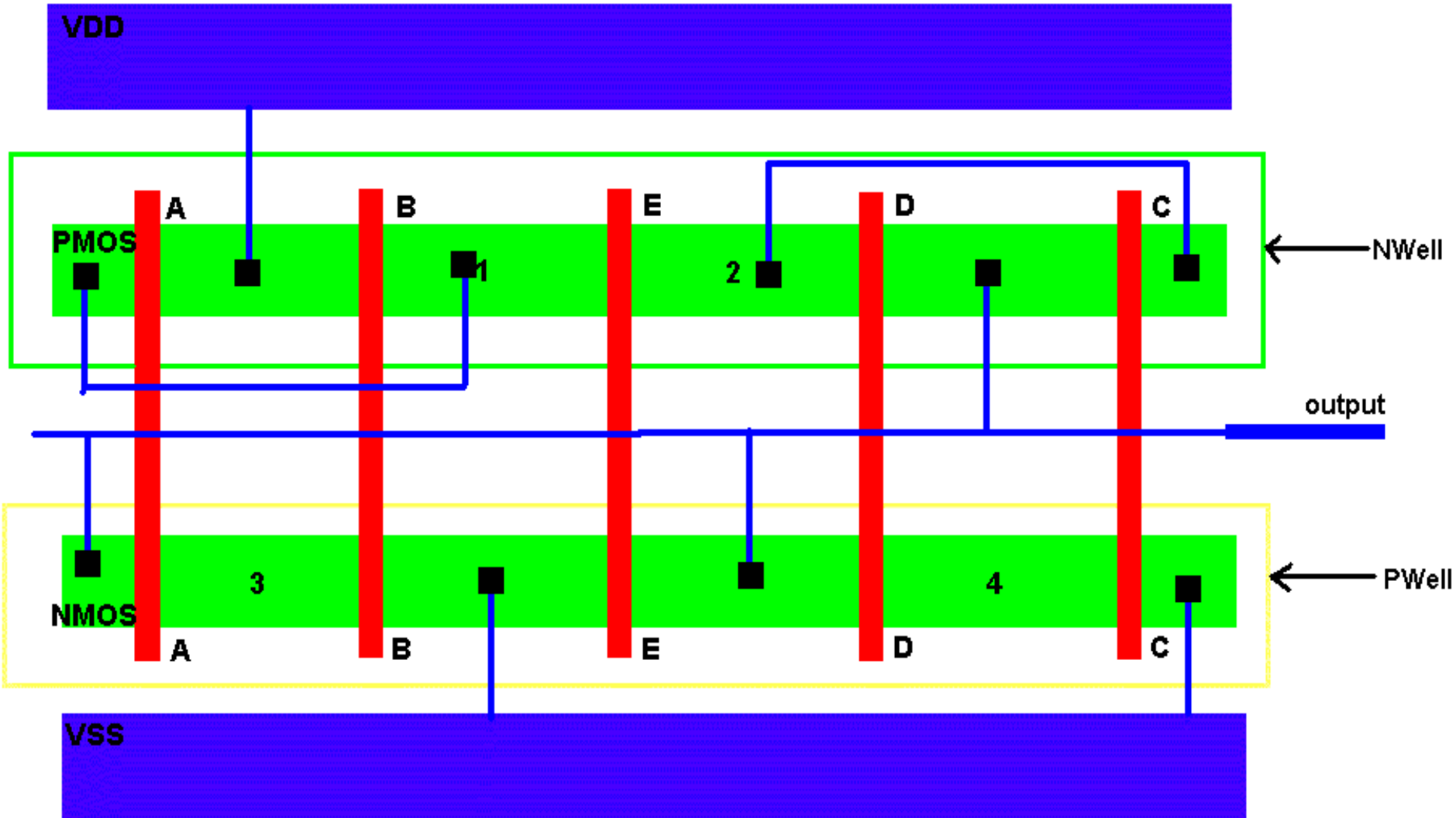
output

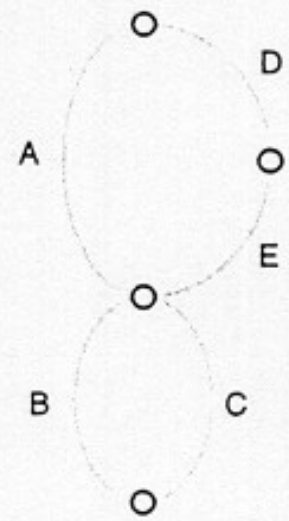
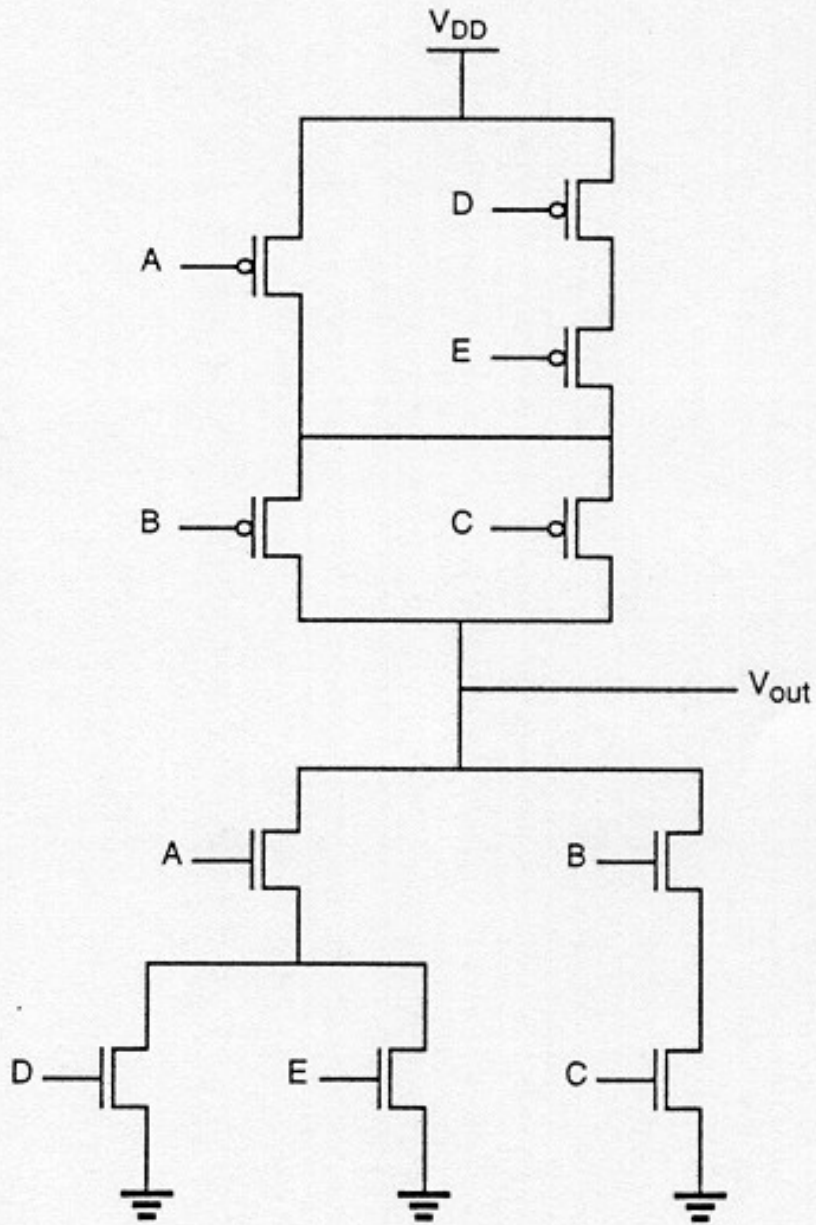


EULER PATH = {A,B,E,D,C}

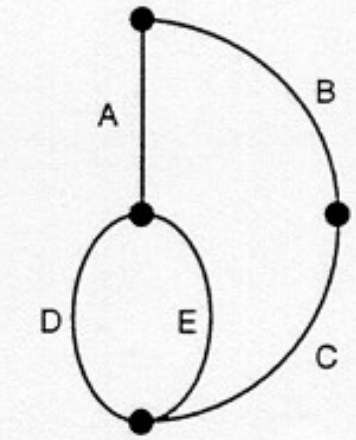
EULER PATH = {A,B,E,D,C}

- METAL 1
- POLY
- ACTIVE





pMOS network graph



nMOS network graph

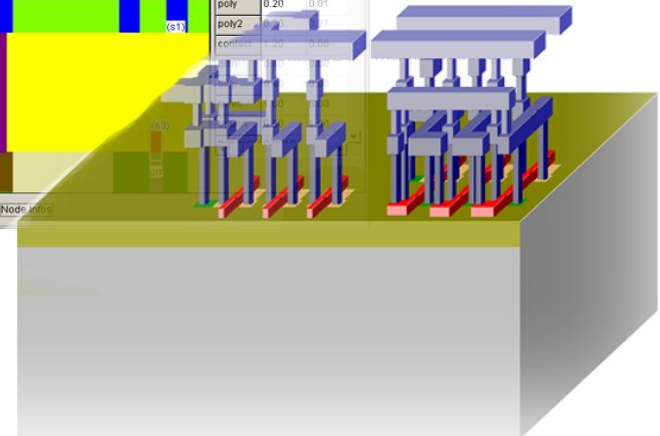
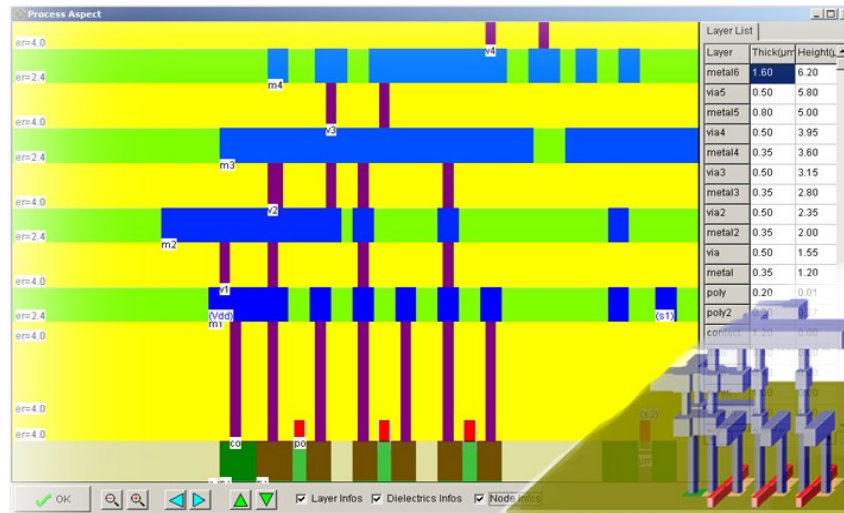
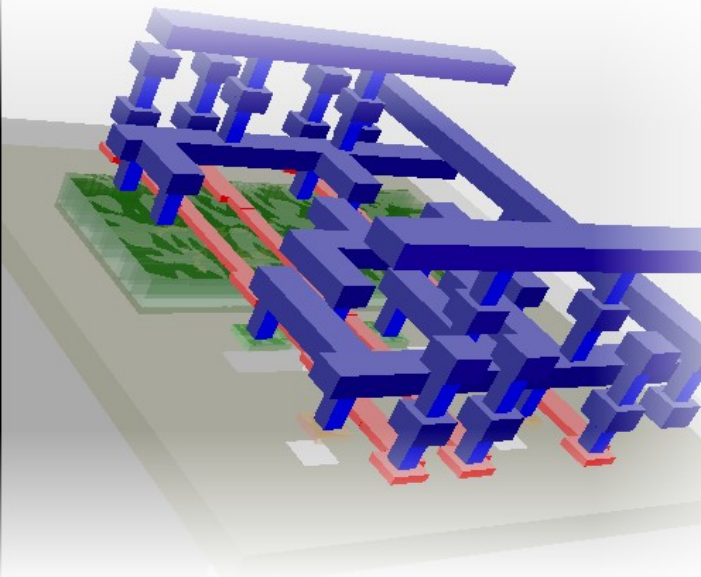




# VirtuosoFab

Touch the deep submicron technology

- 3D fabrication process simulator with cross sectional viewer.
- Step-by-step 3-D visualization of fabrication for any portion of layout.



# 2D Cross Section

## NMOS Transistor

